

Some Defect Counting Microscope Results – Lessons Learned

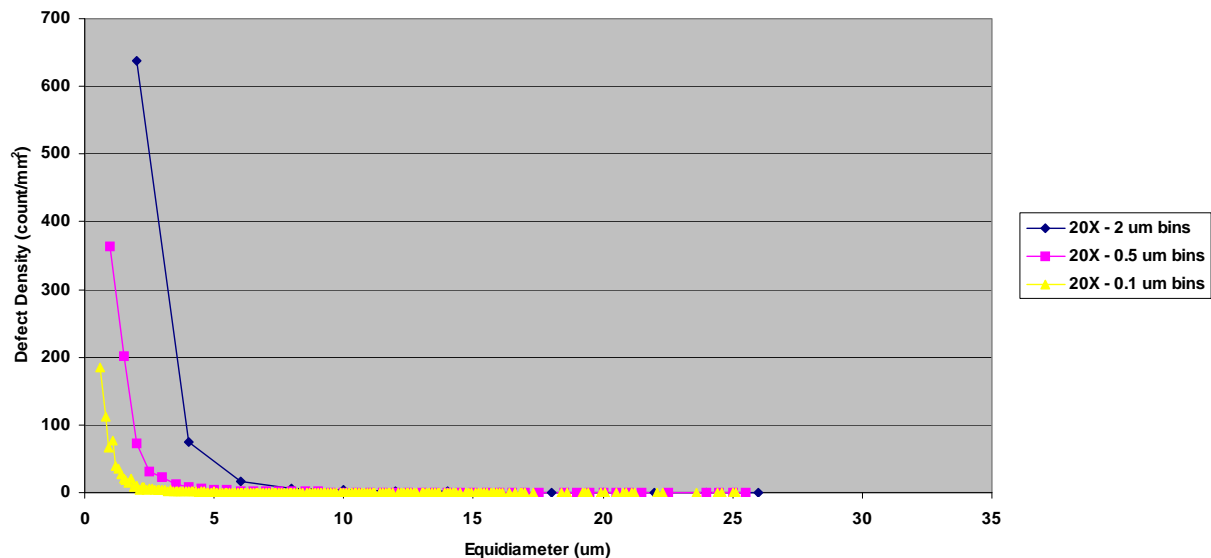
Dark Field Particle Counting on
LMA Micromap Sample
&
Tinsley Scatter Master Sample

LMA Micromap Sample

- 3" diameter fused silica.
- 20X objective, 99 frames analyzed - 26.8 mm² total area.
- Histogram bin size varied: 2 um, 0.5 um, 0.1 um.
- **Same Data manipulated from single map for fixed microscope, contrast & analysis settings.**
- Goal was to understand binning.

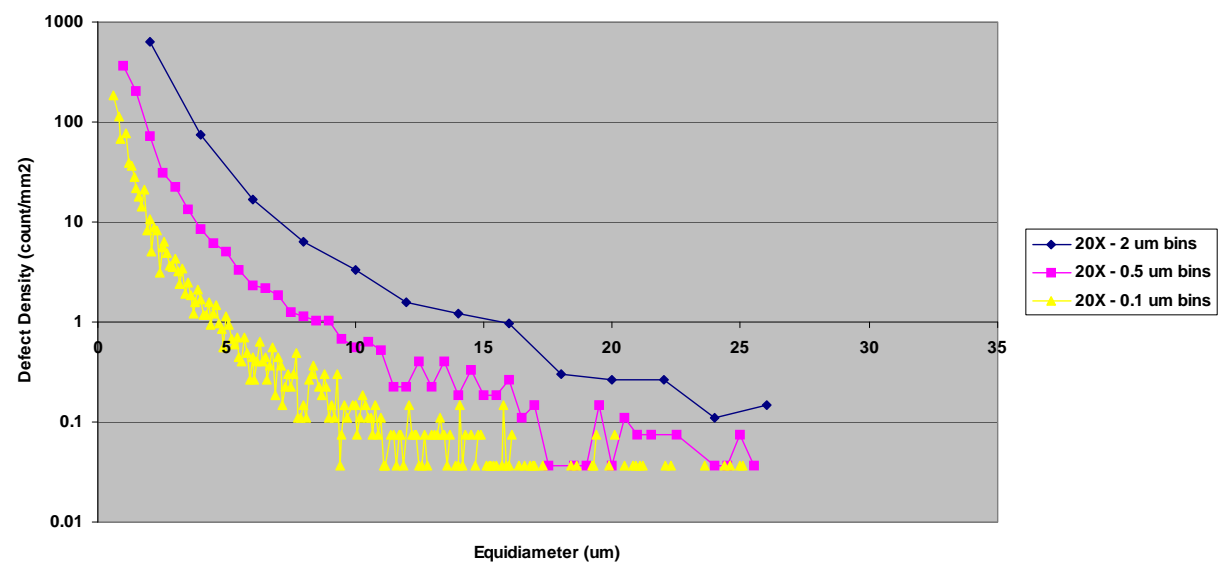
LMA Micromap Sample – Binning: the result can be made nearly independent of the bin size by dividing by the bin size.
 Below, the results are NOT normalized to a bin size.

All 20x Objective, bin size varies



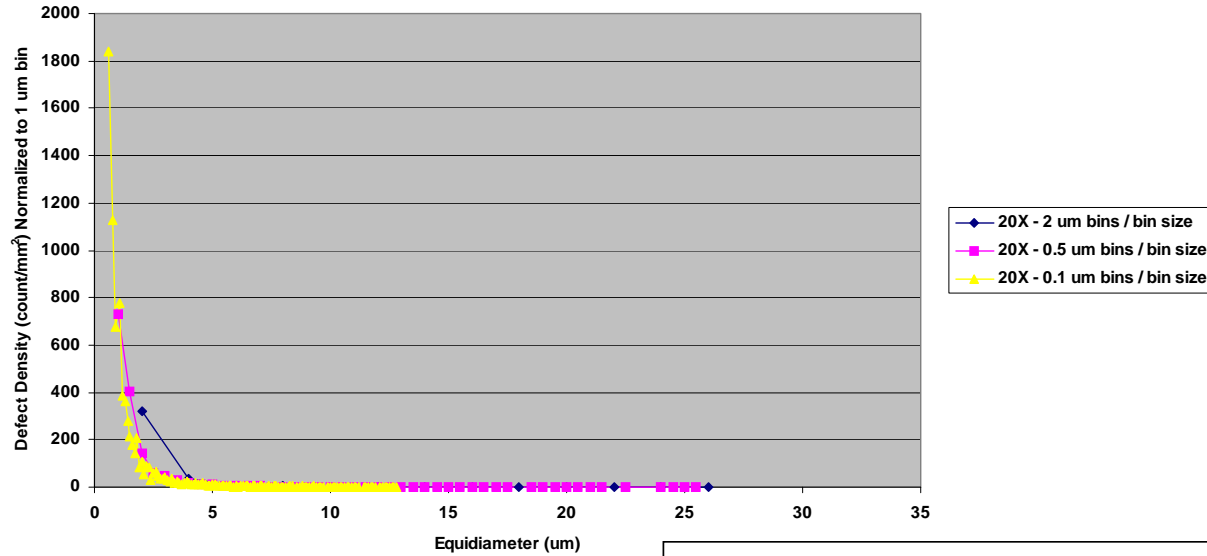
$$Density(E,b) = \frac{counts(E,b)}{A_{total_scanned}}$$

All 20x Objective, bin size varies



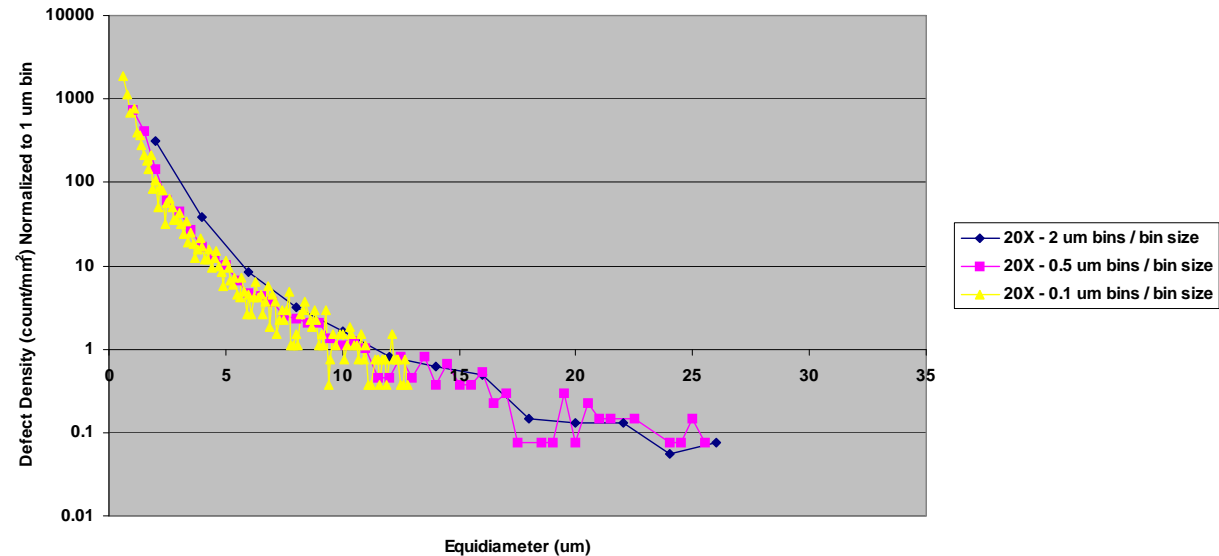
LMA Micromap Sample – Binning: By dividing by the bin size (in microns) the defect density is normalized to a bin size of 1 micron. Larger bin sizes then serve to integrate the data and reduce noise.

All 20x Objective, bin size varies



$$Density_Norm(E,b) = \frac{counts(E,b)}{A_{total_scanned} \cdot b}$$

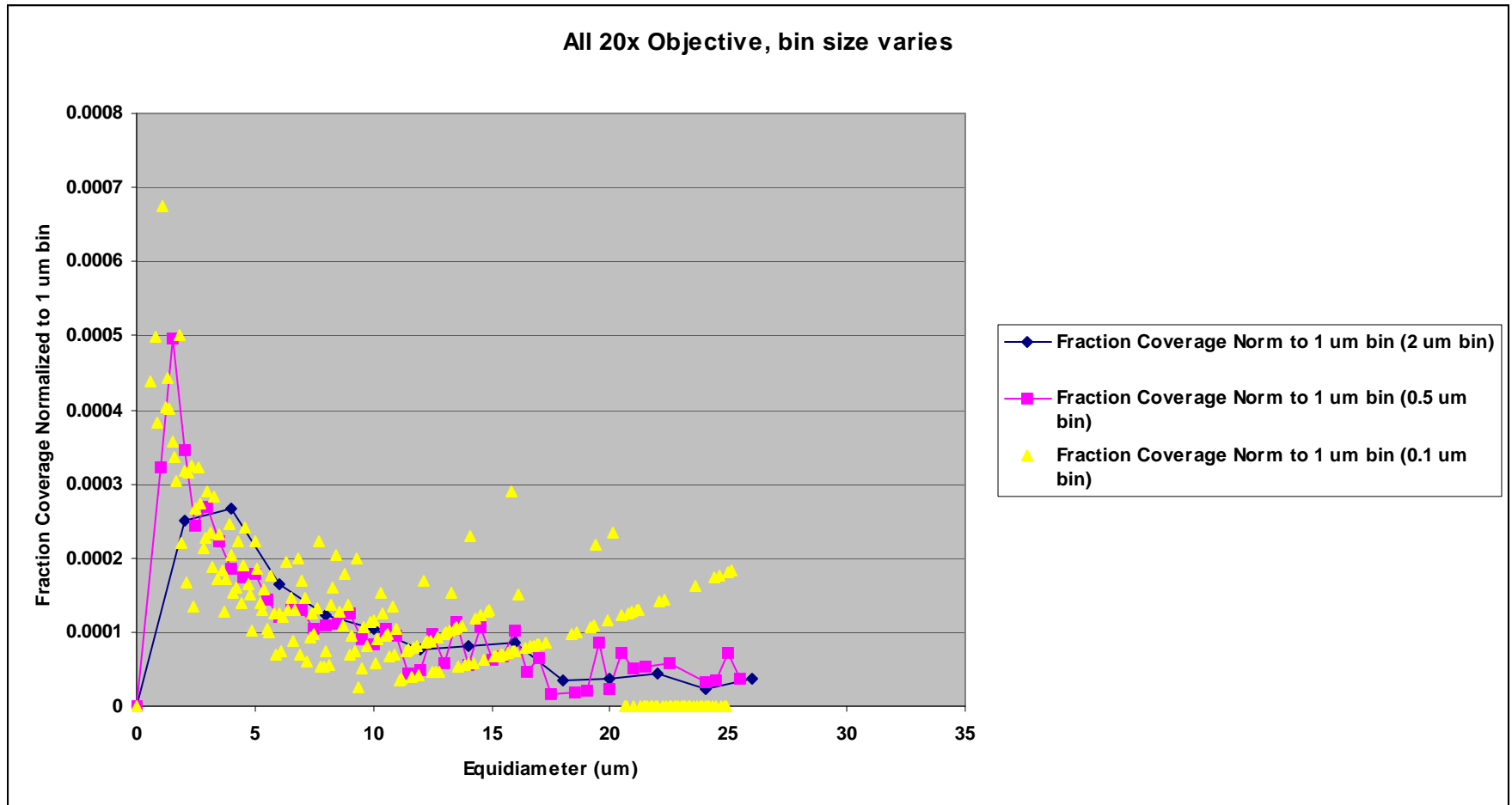
All 20x Objective, bin size varies



LMA Micromap Sample – Conversion of the bin-normalized defect density to a fraction of area covered is done by multiplying by the average defect size S in a bin range at each equidiameter E . The b is the bin size. This produces a peak at the most important equidiameter. Note the peak position is slightly dependent on the bin size. The micromap sample has mostly small defects $1.1 \text{ } \mu\text{m} < E < 1.5 \text{ } \mu\text{m}$, discernable with the smaller bin sizes. Bin sizes that are too big give higher peak values (the 2 μm bin has a peak near 3.5 μm equidiameter).

$$S(E, b) = \pi \left(\frac{1}{2} \frac{E + (E - b)}{2} \right)^2$$

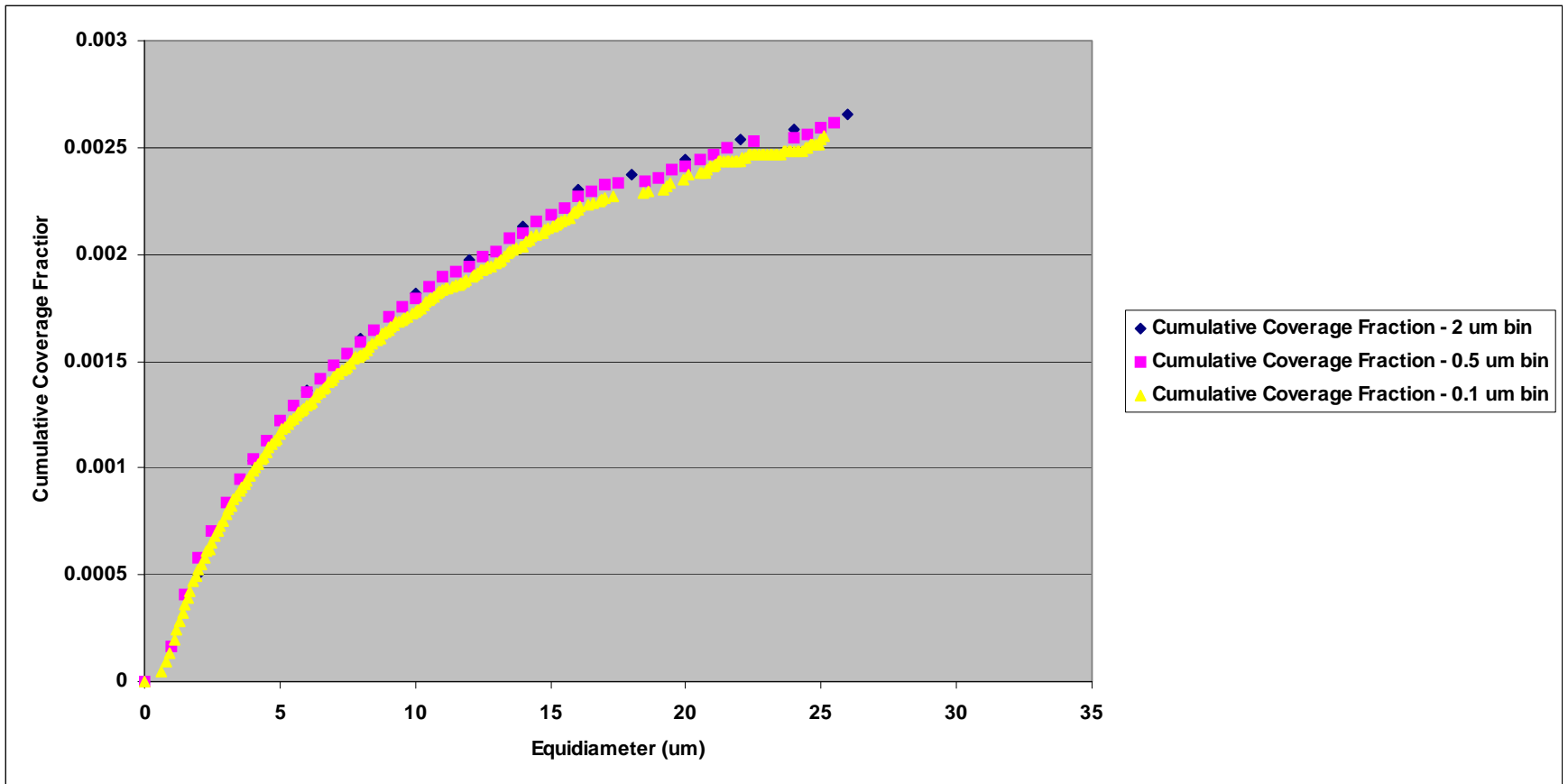
$$FC(E, b) = \frac{\text{counts}(E, b)}{A_{\text{total_scanned}}} \frac{1}{b} S(E, b)$$



LMA Micromap Sample – Integrating over equidiameter then gives the cumulative coverage fraction.

Very weakly bin size dependent.

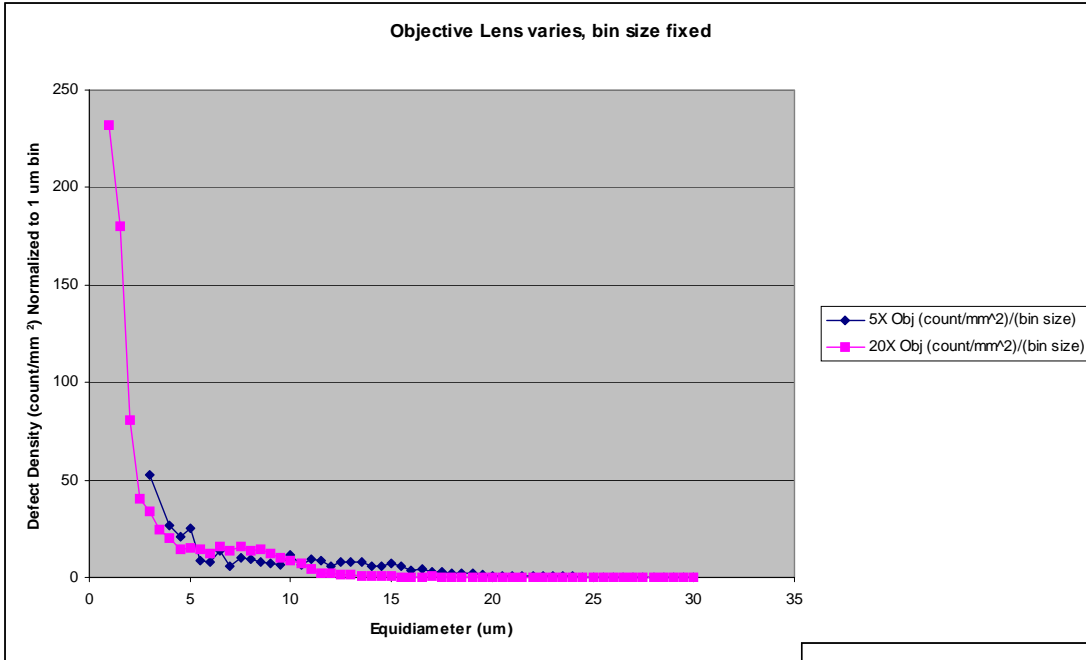
$$\text{Cumulative_FC}(E, b) = b \sum_{\varepsilon=0}^{\varepsilon=E} \text{FC}(\varepsilon, b) = \sum_{\varepsilon=0}^{\varepsilon=E} \text{Density}(\varepsilon, b) S(\varepsilon, b)$$



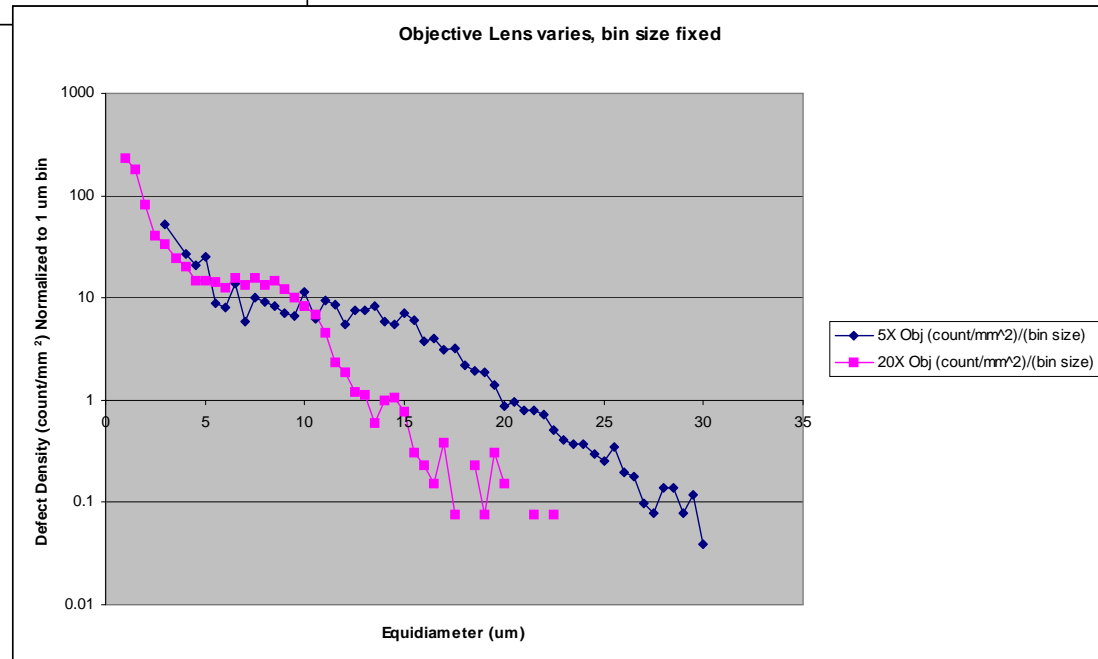
Tinsley Scatter Master Sample

- 1" x 3" microscope slide.
- 20X objective, 99 frames analyzed - 26.8 mm² total area.
- 5X objective, 24 frames analyzed – 102 mm² total area.
- Histogram bin size fixed at 0.5 um.
- **Contrast (exposure time) must change on changing magnification.**
- **Analysis settings (threshold + restrictions) must also change.**

Tinsley Scatter Sample – Defect density normalized to 1 micron bin.

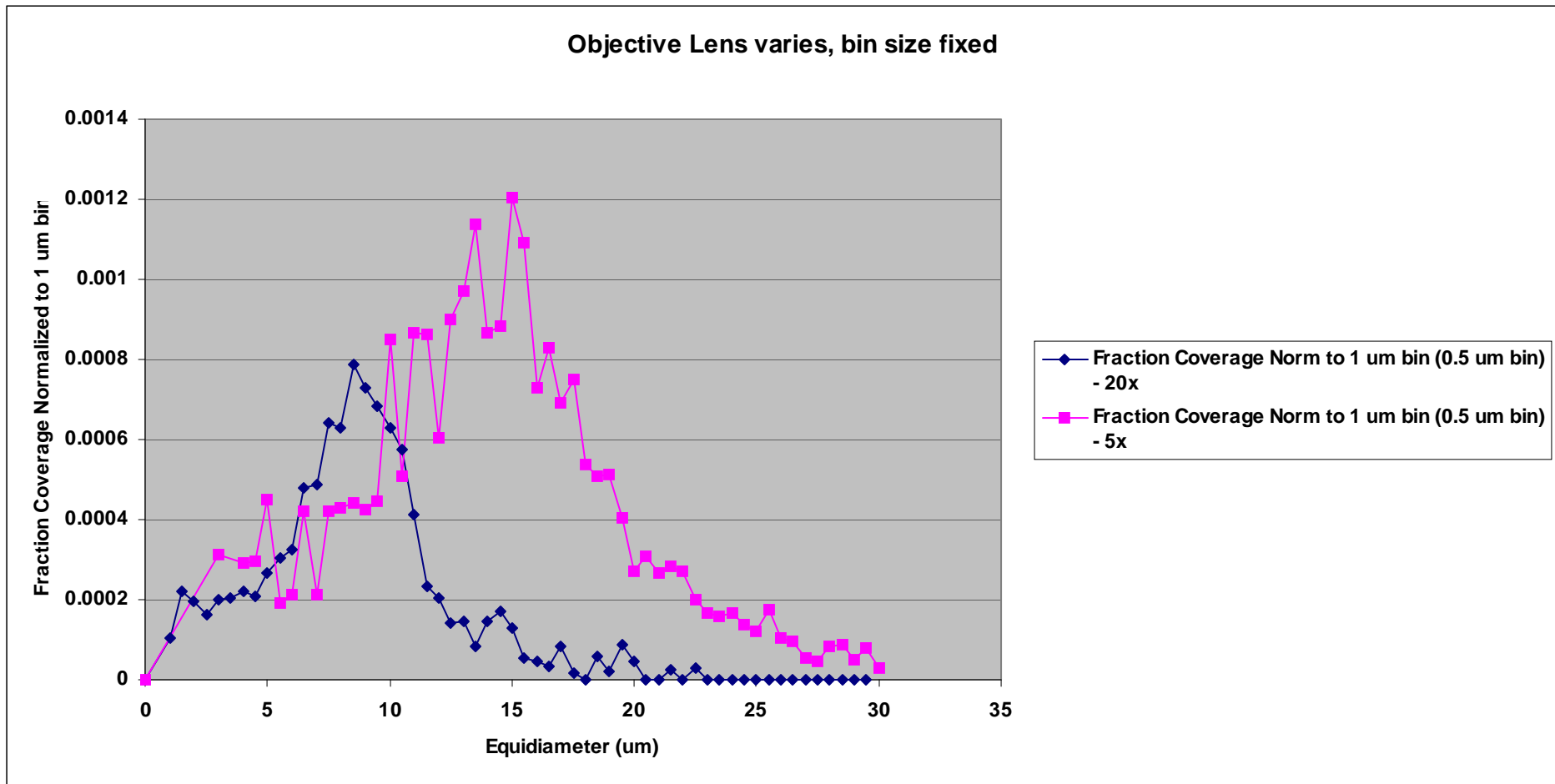


Note that the 5X objective is more sensitive to larger defects, the 20X objective is more sensitive to smaller ones, while in the mid-range they are in closer agreement.



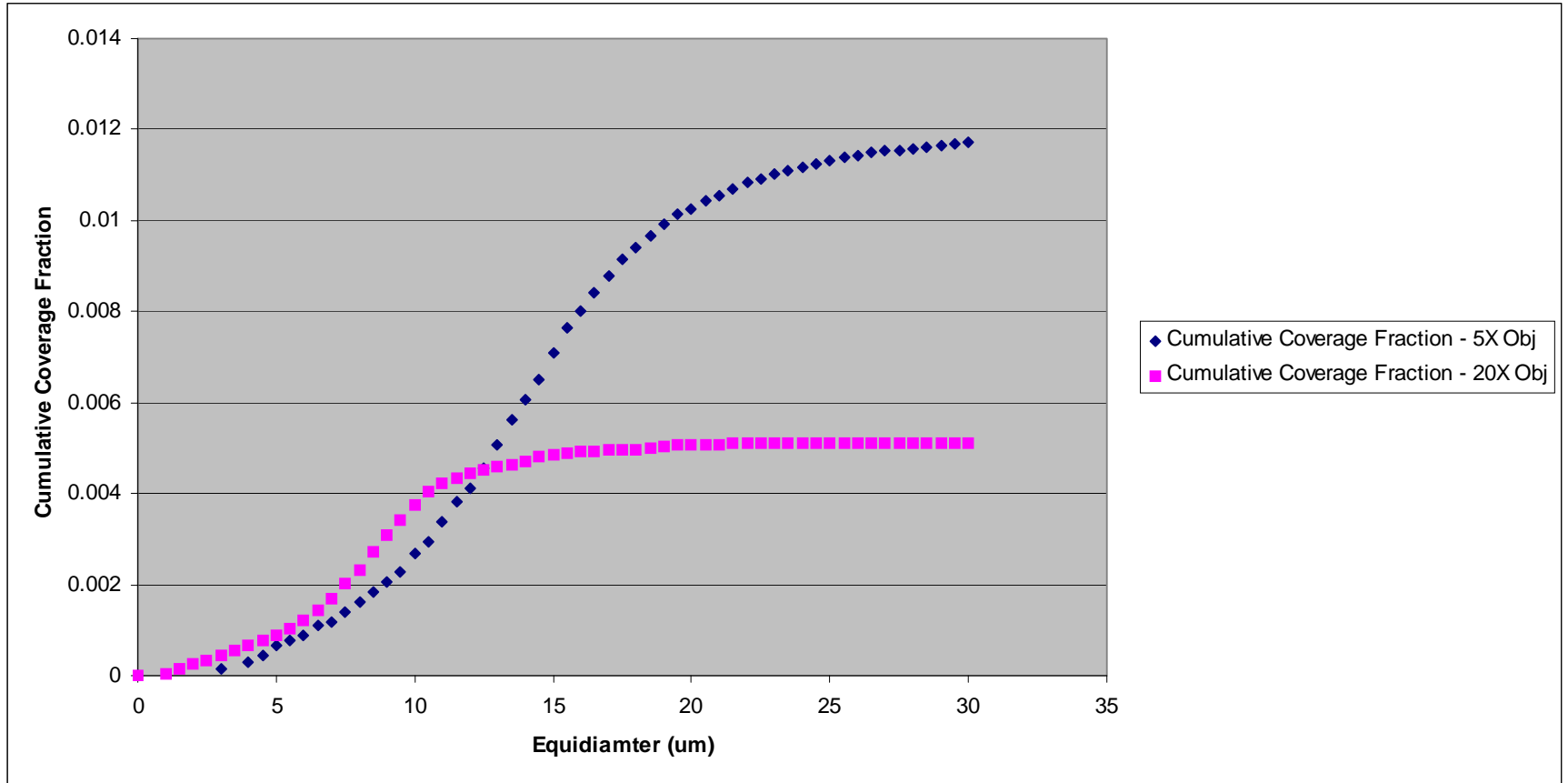
Tinsley Scatter Sample – Coverage Fraction normalized to 1 micron bin.

The peak range varies with the magnification. 5X is 13-16 μm while at 20X the peak range is 7 – 11 μm .



Tinsley Scatter Master Sample – Integrating over equidiameter then gives the cumulative coverage fraction.

Strongly magnification dependent.



Conclusions

- The results thus far seem to be more strongly magnification dependent, and less strongly bin size dependent.
- For a sample type, the bin size and magnification should be standardized before comparing with a scatter measurement.
- How to standardize will come with experience in analyzing real samples that are routinely generated.